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Thin Solid Films 277 (1996) 197

thin solid films

Author Index of Volume 277

Adler, M., 7
Alonso, P., 192
Asai, K., 169

Barraud, A., 7
Bender, H., 90
Bennouna, A., 155
Bica de Moraes, M.A., 115
Broitman, E., 192
Brunel, M., 138

Chen, D.-G., 162
Churaev, N.V., 7
Crnjak Orel, Z., 185

Durrant, S.F., 115

Eaton, D.F., 7

Hauser, J.R., 101
Hrdina, J., 83

Ishigure, K., 169

Jadhav, U.S., 5
Jain, A., 128
Jergel, M., 138

Kale, S.S., 5
Kanai, M., 98
Kataoka, H., 132
Kawai, T., 98
Klanjšek Gunde, M., 185
Kožar Logar, J., 185
Kozuka, H., 147
Kuhn, H., 7

Laaziz, Y., 155
Lampert, C.M., 162
Lee, H., 98
Leggieri, G., 138
Lim, S., 144
Lokhande, C.D., 5
Luby, S., 138
Luches, A., 138

Maex, K., 90
Majkova, E., 138
Majni, G., 138
Mengucci, P., 138
Misono, M., 7
Mizuno, K., 175
Mochizuki, M., 180

Nagata, H., 132

Olszyna, A., 79
Orel, B., 185
Özer, N., 162

Platikanov, D., 7

Ralston, J., 7

Sakata, J., 180
Sanders, J.H., 121
Setsune, K., 175
Shibata, H., 169
Shibata, S., 1
Shih, S., 144
Silberberg, A., 7
Silvestre, C., 101
Sobota, J., 83
Srivastav, S., 128

Takahashi, H., 132
Tavares, J., 90
Ter Minassian-Saraga, L., 7
Tikhonravov, A.V., 83
Trubetskov, M.K., 83

Vincent, B., 7

Wager, J.F., 144
Wagh, B.G., 5

Yamaki, T., 169
Yoko, T., 147

Zemel, J.N., 7
Zhao, G., 147
Zimmerman, R., 192

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ELSEVIER

Thin Solid Films 277 (1996) 198–199

thin solid films

Subject Index of Volume 277

Acetylene
dynamic actinometric optical emission spectroscopy for the elucidation of plasma processes in the production of fluorinated amorphous hydrogenated carbon films from glow discharges, 115
Adhesion
treatment of MoS_2 films by high-energy heavy ion beams, 128
Aluminium
investigation of grain boundary chemistry in Al-Li 2195 welds using Auger electron spectroscopy, 121
Amorphous materials
Ar/H_2 sputtering deposition of 350 μm thick $Si:H/SiO_{2-x}:H$ multilayers having flat interfaces for optical applications, 132
Anisotropy
preparation of uniaxially oriented polyamide films by vacuum deposition polymerization, 180
Auger electron spectroscopy
investigation of grain boundary chemistry in Al-Li 2195 welds using Auger electron spectroscopy, 121

Benzene
dynamic actinometric optical emission spectroscopy for the elucidation of plasma processes in the production of fluorinated amorphous hydrogenated carbon films from glow discharges, 115
Boron nitride
deposition of BN coatings by spraying a powder accelerated electrodynamically in a coaxial pulse plasma generator, 79

Cadmium selenide
ion bombardment effect on electronic states in CdS fine particles, 169
Chemical vapour deposition
preparation of uniaxially oriented polyamide films by vacuum deposition polymerization, 180
Coatings
treatment of MoS_2 films by high-energy heavy ion beams, 128
optimum thickness determination to maximise the spectral selectivity of black pigmented coatings for solar collectors, 185
Conductivity
studies on metal contact to polyaniline films, 5
deviations from Matthiessen's rule in continuous metal films, 192
Copper
studies on metal contact to polyaniline films, 5
stability of interfaces in Mo/Cu multilayered metallization, 138

Deposition process
dielectric constants of Ta_2O_5 thin films deposited by r.f. sputtering, 1
preparation of uniaxially oriented polyamide films by vacuum deposition polymerization, 180
Depth profiling
characterization of quasi-rugate filters using ellipsometric measurements, 83
Dielectrics
dielectric constants of Ta_2O_5 thin films deposited by r.f. sputtering, 1

Elsevier Science S.A.

Electrical properties and measurements
deviations from Matthiessen's rule in continuous metal films, 192
Electrochemistry
preparation and properties of spin-coated Nb_2O_5 films by the sol–gel process for electrochromic applications, 162
Electron diffraction
transmission electron microscopy characterisation of ion beam synthesised $FeSi_2$ layers, 90
Electron scattering
deviations from Matthiessen's rule in continuous metal films, 192
Ellipsometry
characterization of quasi-rugate filters using ellipsometric measurements, 83
Epitaxy
transmission electron microscopy characterisation of ion beam synthesised $FeSi_2$ layers, 90

Grain boundary
investigation of grain boundary chemistry in Al-Li 2195 welds using Auger electron spectroscopy, 121

Hardness
treatment of MoS_2 films by high-energy heavy ion beams, 128
High energy electron diffraction
crystallinity for epitaxial thin films of Bi-based oxide superconductor prepared at low temperature, 175

Insulators
time-dependent dielectric breakdown measurements on RPECVD and thermal oxides, 101
Interfaces
Ar/H_2 sputtering deposition of 350 μm thick $Si:H/SiO_{2-x}:H$ multilayers having flat interfaces for optical applications, 132
stability of interfaces in Mo/Cu multilayered metallization, 138
Ion bombardment
treatment of MoS_2 films by high-energy heavy ion beams, 128
ion bombardment effect on electronic states in CdS fine particles, 169

Langmuir–Blodgett films
ion bombardment effect on electronic states in CdS fine particles, 169
Laser ablation
preparation of transition metal chalcogenide thin films by pulsed laser ablation, 98
Light scattering
optimum thickness determination to maximise the spectral selectivity of black pigmented coatings for solar collectors, 185
Luminescence
ion bombardment effect on electronic states in CdS fine particles, 169

Metal–oxide semiconductor structure
time-dependent dielectric breakdown measurements on RPECVD and thermal oxides, 101

Metals
investigation of grain boundary chemistry in Al-Li 2195 welds using Auger electron spectroscopy, 121
sol–gel preparation and photoelectrochemical properties of TiO_2 films containing Au and Ag metal particles, 147
Molybdenum
stability of interfaces in Mo/Cu multilayered metallization, 138
Multilayers
stability of interfaces in Mo/Cu multilayered metallization, 138

Niobium
preparation of transition metal chalcogenide thin films by pulsed laser ablation, 98
Niobium oxide
preparation and properties of spin-coated Nb_2O_5 films by the sol–gel process for electrochromic applications, 162

Optical coatings
characterization of quasi-rugate filters using ellipsometric measurements, 83
Ar/H_2 sputtering deposition of 350 μm thick $Si:H/SiO_{2-x}:H$ multilayers having flat interfaces for optical applications, 132
design and fabrication of a double bandstop rugate filter grown by plasma-enhanced chemical vapor deposition, 144
Optical properties
on some important care to take when making spectrophotometric measurements on semiconductor thin films, 155
preparation and properties of spin-coated Nb_2O_5 films by the sol–gel process for electrochromic applications, 162
optimum thickness determination to maximise the spectral selectivity of black pigmented coatings for solar collectors, 185

Plasma processing and deposition
deposition of BN coatings by spraying a powder accelerated electrodynamically in a coaxial pulse plasma generator, 79
time-dependent dielectric breakdown measurements on RPECVD and thermal oxides, 101
dynamic actinometric optical emission spectroscopy for the elucidation of plasma processes in the production of fluorinated amorphous hydrogenated carbon films from glow discharges, 115
design and fabrication of a double bandstop rugate filter grown by plasma-enhanced chemical vapor deposition, 144
Polymers
studies on metal contact to polyaniline films, 5
preparation of uniaxially oriented polyamide films by vacuum deposition polymerization, 180

Reflection spectroscopy
optimum thickness determination to maximise the spectral selectivity of black pigmented coatings for solar collectors, 185
Resistivity
deviations from Matthiessen's rule in continuous metal films, 192
Rutherford backscattering spectroscopy
crystallinity for epitaxial thin films of Bi-based oxide superconductor prepared at low temperature, 175

Semiconductors
studies on metal contact to polyaniline films, 5
on some important care to take when making spectrophotometric measurements on semiconductor thin films, 155
Silicides
transmission electron microscopy characterisation of ion beam synthesised $FeSi_2$ layers, 90
Silicon nitride
design and fabrication of a double bandstop rugate filter grown by plasma-enhanced chemical vapor deposition, 144
Silicon oxide
time-dependent dielectric breakdown measurements on RPECVD and thermal oxides, 101
design and fabrication of a double bandstop rugate filter grown by plasma-enhanced chemical vapor deposition, 144
Solar cells
sol–gel preparation and photoelectrochemical properties of TiO_2 films containing Au and Ag metal particles, 147
Sputtering
dielectric constants of Ta_2O_5 thin films deposited by r.f. sputtering, 1
on some important care to take when making spectrophotometric measurements on semiconductor thin films, 155
Stress
Ar/H_2 sputtering deposition of 350 μm thick $Si:H/SiO_{2-x}:H$ multilayers having flat interfaces for optical applications, 132
Sulphur
preparation of transition metal chalcogenide thin films by pulsed laser ablation, 98
Sulphur hexafluoride
dynamic actinometric optical emission spectroscopy for the elucidation of plasma processes in the production of fluorinated amorphous hydrogenated carbon films from glow discharges, 115
Superconductivity
crystallinity for epitaxial thin films of Bi-based oxide superconductor prepared at low temperature, 175
Surface defects
on some important care to take when making spectrophotometric measurements on semiconductor thin films, 155
Surface plasmons
sol–gel preparation and photoelectrochemical properties of TiO_2 films containing Au and Ag metal particles, 147

Tantalum
dielectric constants of Ta_2O_5 thin films deposited by r.f. sputtering, 1
Titanium oxide
sol–gel preparation and photoelectrochemical properties of TiO_2 films containing Au and Ag metal particles, 147
Transmission electron microscopy
transmission electron microscopy characterisation of ion beam synthesised $FeSi_2$ layers, 90

X-ray diffraction
crystallinity for epitaxial thin films of Bi-based oxide superconductor prepared at low temperature, 175
X-ray photoelectron spectroscopy
preparation and properties of spin-coated Nb_2O_5 films by the sol–gel process for electrochromic applications, 162